

**AMENDMENTS TO THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

Claims 1-61 (Canceled).

62. (Currently Amended) A nitride semiconductor light emitting device comprising;

- a substrate,
- a first nitride semiconductor layer being undoped and ~~having an impurity concentration less than  $1 \times 10^{17}/\text{cm}^3$ , said first nitride semiconductor layer being a single~~ layer,
- a second nitride semiconductor layer having an n-type electrode and, ~~said second nitride semiconductor layer being a single layer,~~
- a third nitride semiconductor layer being undoped ~~having an impurity concentration less than  $1 \times 10^{17}/\text{cm}^3$ , said third nitride semiconductor layer and~~ being a super lattice layer of InGaN layers and GaN layers, and
- a separate and distinct active layer where electrons and holes are combined.

63. (Previously Presented) The nitride semiconductor light emitting device according to claim 62;

wherein said second nitride semiconductor layer is made of GaN or AlGaN and said second nitride semiconductor layer includes Si as an n-type impurity.

64. (Previously Presented) The nitride semiconductor light emitting device according to claim 62;

wherein said first nitride semiconductor layer is made of GaN or AlGaN.

65. (Previously Presented) The nitride semiconductor light emitting device according to claim 62;

wherein said second nitride semiconductor layer has an carrier concentration more than  $3 \times 10^{18}/\text{cm}^3$ .

66. (Previously Presented) The nitride semiconductor light emitting device according to claim 62;

wherein said second nitride semiconductor layer has a resistivity less than  $8 \times 10^{-3} \text{ ohm} \cdot \text{cm}$ .

67. (Previously Presented) The nitride semiconductor light emitting device according to claim 62;

further comprising a buffer layer between said substrate and said first nitride semiconductor layer.

68. (Previously Presented) The nitride semiconductor light emitting device according to claim 62;

wherein said first nitride semiconductor layer has a thickness within a range of from 0.1 to 20  $\mu\text{m}$ .

69. (Previously Presented) The nitride semiconductor light emitting device according to claim 62;

wherein said second nitride semiconductor layer has a thickness within a range of from 0.1 to 20  $\mu\text{m}$ ,

70. (Currently Amended) A nitride semiconductor light emitting device comprising:

a substrate,

a first nitride semiconductor layer being undoped ~~having an impurity concentration less than  $1 \times 10^{17}/\text{cm}^3$ , said first nitride semiconductor layer~~ and being a single layer,

a second nitride semiconductor layer having an n-type electrode, ~~said second nitride semiconductor layer~~ and being a single layer,

a third nitride semiconductor layer being a super lattice layer of GaN layers, and

a separate and distinct active layer where electrons and holes are combined.

71. (Previously Presented) The nitride semiconductor light emitting device according to claim 70;

wherein said second nitride semiconductor layer is made of GaN or AlGaN and said second nitride semiconductor layer includes Si as an n-type impurity.

72. (Previously Presented) The nitride semiconductor light emitting device according to claim 70;

wherein said first nitride semiconductor layer is made of GaN or AlGaN

73. (Previously Presented) The nitride semiconductor light emitting device according to claim 70;

wherein said second nitride semiconductor layer has a carrier concentration more than  $3 \times 10^{18}/\text{cm}^3$ .

74. (Previously Presented) The nitride semiconductor light emitting device according to claim 70;

wherein said second nitride semiconductor layer has a resistivity less than  $8 \times 10^{-3} \text{ ohm} \cdot \text{cm}$ .

75. (Previously Presented) The nitride semiconductor light emitting device according to claim 70;

further comprising a buffer layer between said substrate and said first nitride semiconductor layer.

76. (Previously Presented) The nitride semiconductor light emitting device according to claim 70;

wherein said first nitride semiconductor layer has a thickness within a range of from 0.1 to 20  $\mu\text{m}$ ,

77. (Previously Presented) The nitride semiconductor light emitting device according to claim 70;

wherein said second nitride semiconductor layer has a thickness within a range of from 0.1 to 20  $\mu\text{m}$ .

78. (Previously Presented) The nitride semiconductor light emitting device according to claim 70;

wherein said third nitride semiconductor layer being a super lattice layer of undoped GaN layers and Si doped GaN layers.

79. (Previously Presented) The nitride semiconductor light emitting device according to claim 78;

wherein said Si doped GaN layers are doped with Si to  $1 \times 10^{19}/\text{cm}^3$ .

80. (Previously Presented) The nitride semiconductor light emitting device according to claim 78;

wherein said undoped GaN layers have a thickness of 75Å and Si doped GaN layers have a thickness of 25Å.

81. (Previously Presented) The nitride semiconductor light emitting device according to claim 78;

wherein said third nitride semiconductor layer has a thickness of 600Å.